

# GaAs Substrate Recycling Using *in-situ* Deposited NaCl Layers via Molecular Beam Epitaxy

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# Introduction: III-V Substrate Recycling

Substrate cost is large part of total cell cost

Existing methods of substrate reuse:

Mechanical exfoliation    Chemical wet etch

**fast**  
**rough**

**smoother**

**slower**

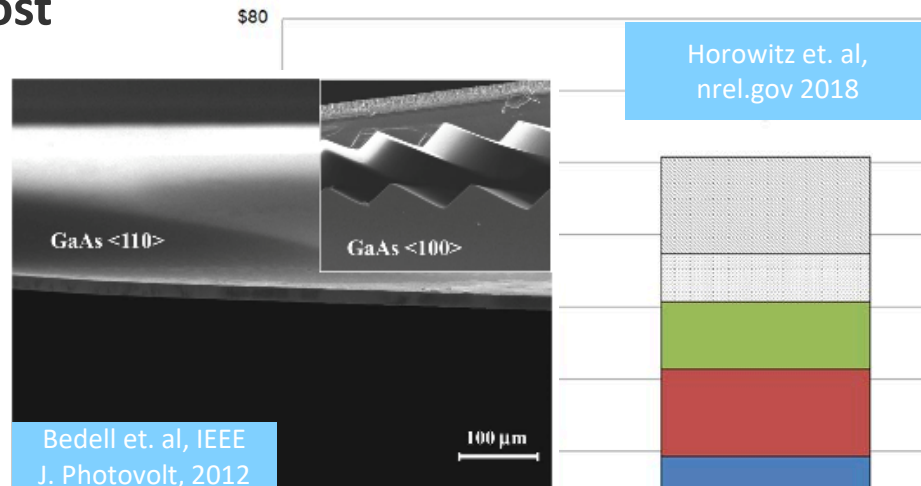
**toxic**

**Al selective**

Other sacrificial layers? ... NaCl?

- Highly water soluble
- Non-toxic
- NaCl has history in MBE

\$80



Bedell et. al, IEEE  
J. Photovolt, 2012



te  
=30%)

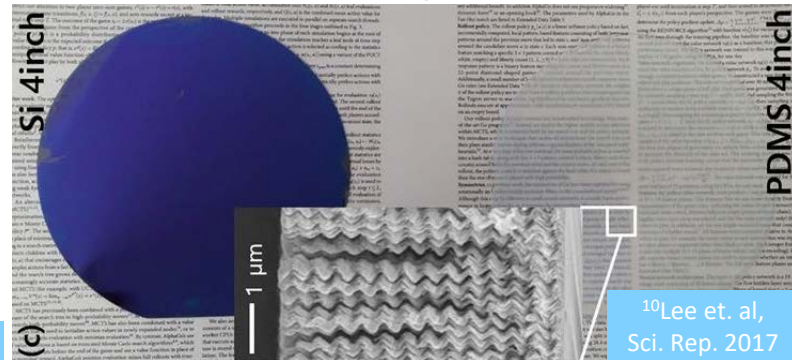
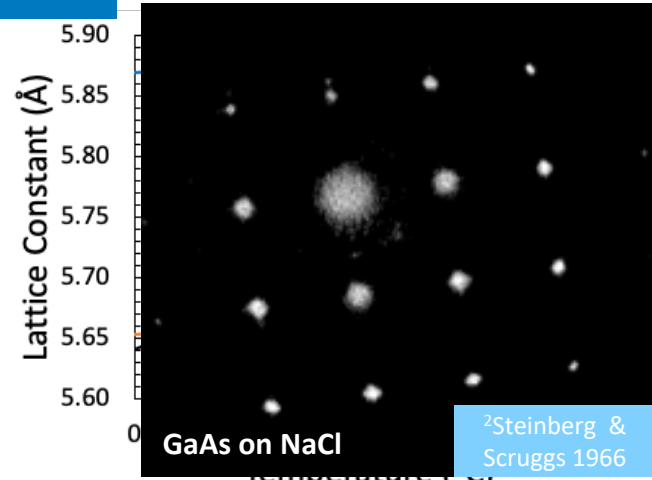
# Previous Growth on NaCl

One of the first substrates for epitaxy of metals and semiconductors

- III-V on NaCl first in 1960s in a bell jar<sup>1,2</sup>
- Si<sup>3</sup>, Ge<sup>4,5</sup>, SnS<sup>6</sup>, CdS/InP<sup>7</sup>

No reports of liftoff of true epitaxial single crystal overlayers on NaCl

NaCl and GaAs lattice matched at ~100°C



<sup>1</sup>Evans & Noreika Philosophical Mag 1966, <sup>2</sup>Steinberg & Scruggs, J.Appl Phys 1966) <sup>3</sup>Shimoaka et al, JVSTB 1972, <sup>4</sup>Shimoaka et al, JVSTB 1971, <sup>5</sup>Barkai et al, Thin Solid Films 1980, <sup>6</sup>Wangperawaong et al, APL 2013, <sup>7</sup>Neelkanth et al, JVST 1980, <sup>8</sup>Tiwari et al, Prog. Photovolt: Res. Apply. 1999, <sup>9</sup>Tiwari et al, Prog. Photovolt: Res. Apply. 1999, <sup>10</sup>Lee et al, Sci Rep. 2017,

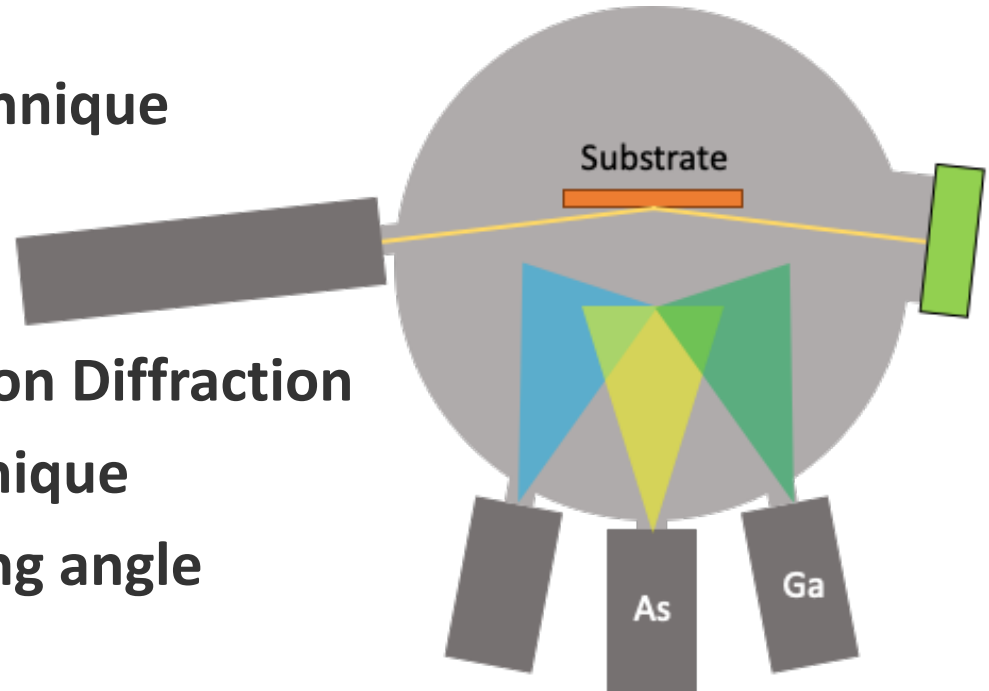
# MBE and RHEED

## Molecular Beam Epitaxy

- High purity deposition technique
- Ultra-high vacuum
- NaCl compound source

## Reflection High Energy Electron Diffraction

- *In-situ* measurement technique
- Surface analysis via glancing angle electron diffraction



# Reciprocal Space & RHEED Patterns

Atoms in reciprocal space:  $k_x = 2\pi/a$

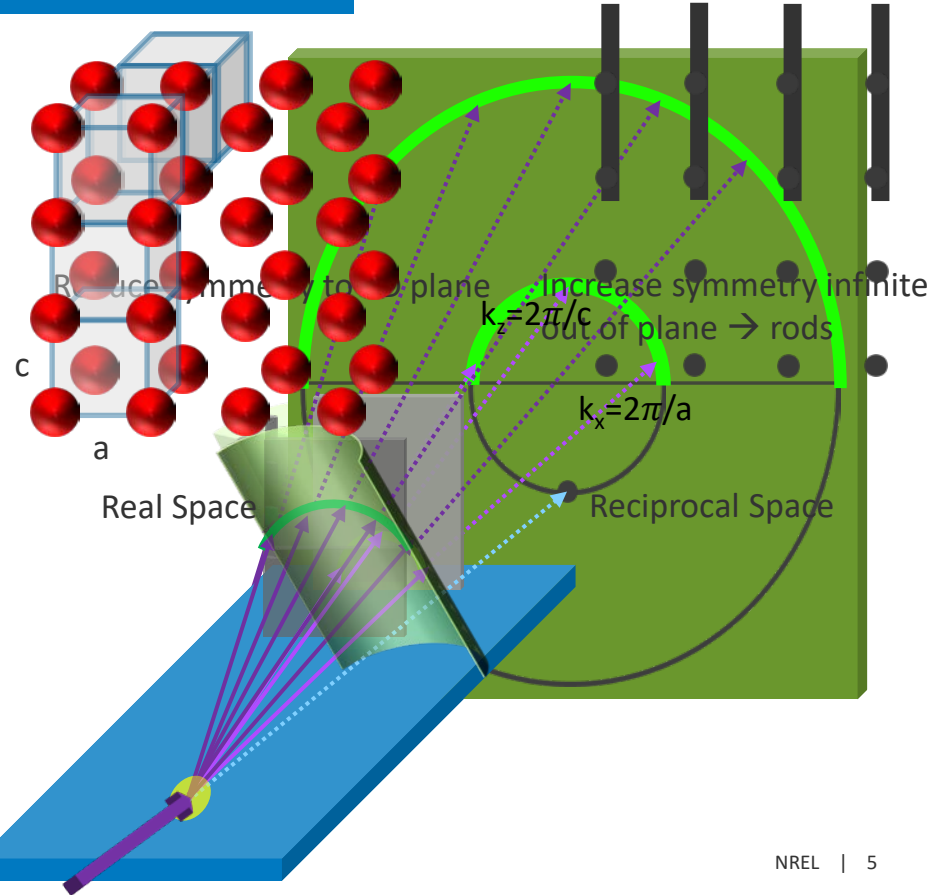
Diffraction conditions: Ewald Sphere

Typical surface patterns:

- Real smooth surface  $\rightarrow$  Streaks
- Rough surface  $\rightarrow$  Spots
- Polycrystalline  $\rightarrow$  Rings

Additional patterns:

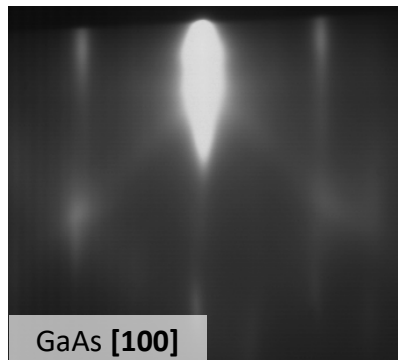
- Faceted surface  $\rightarrow$  Chevrons
- Twins  $\rightarrow$  Spot shadows



# NaCl on GaAs: *In-situ* Measurements

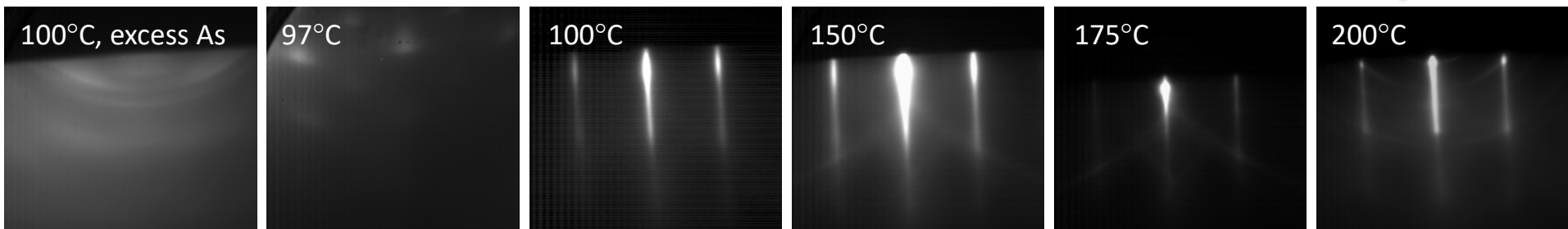
First step is to grow NaCl on GaAs (001)

- ~30nm of NaCl
- Growth rate of 3 nm/min



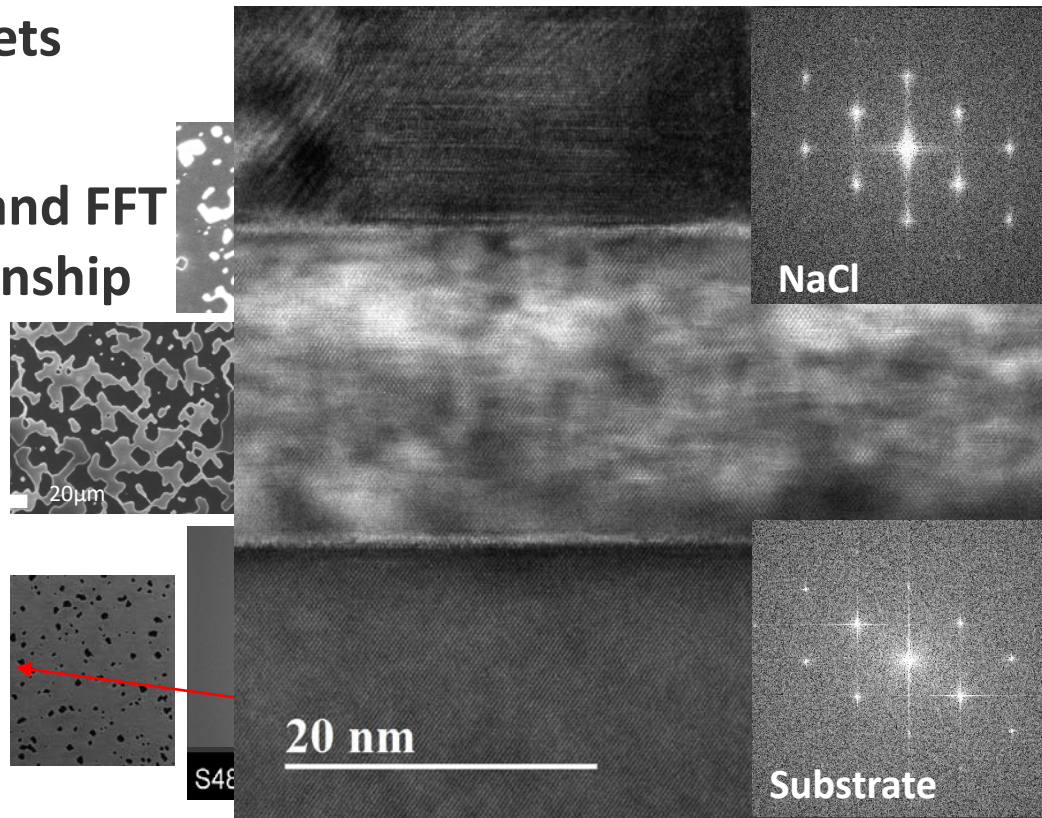
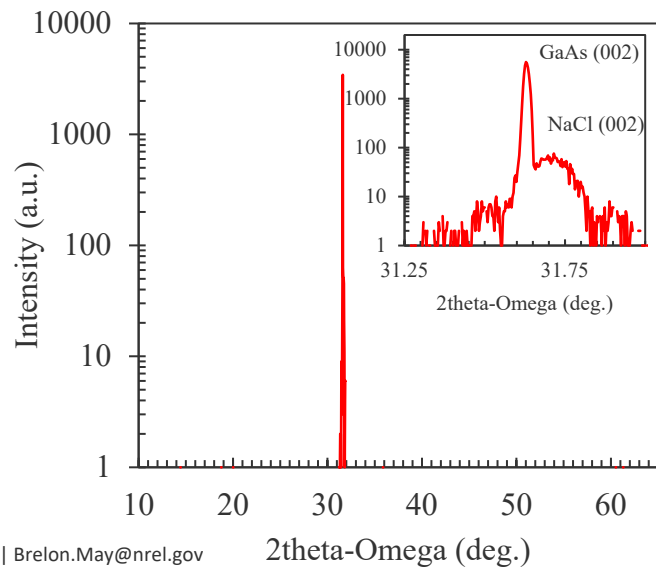
- Important to have clean starting surface
- $T_{\text{sub}} < 100^{\circ}\text{C} \rightarrow$  3D growth
- $T_{\text{sub}} \geq 200^{\circ}\text{C} \rightarrow$  Polycrystalline

Increasing Temperature



# NaCl on GaAs: *Ex-situ Measurements*

- SEM shows NaCl with {100} facets
- XRD shows single phase
- TEM shows smooth interfaces and FFT patterns reveal epitaxial relationship



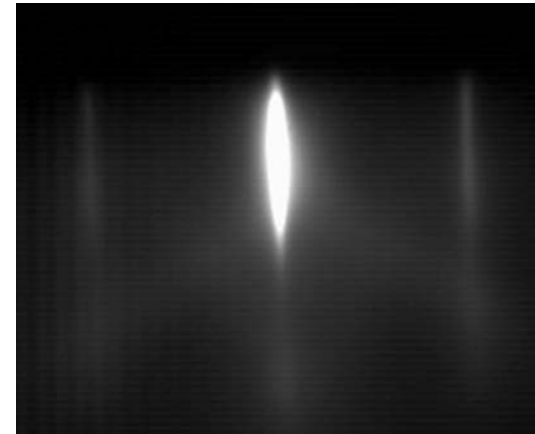
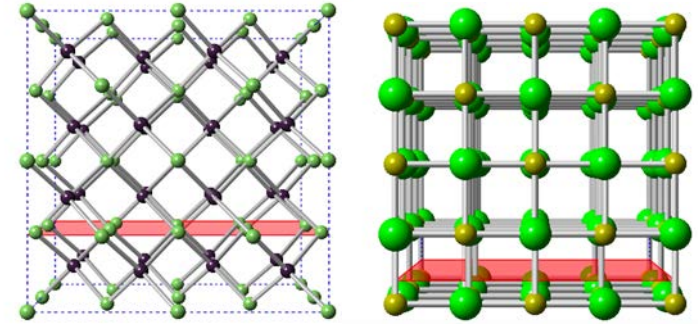
# GaAs on Salt: The Problems

This is complicated chemically and structurally

- **Heterovalent interface**
  - NaCl – 6 ionic bonds
  - GaAs – 4 covalent bonds
- **Symmetry Mismatch** → APDs & twins
- **Not actually lattice matched**
  - GaAs typically grown at  $\sim 580^{\circ}\text{C}$  → (+3%)

**Initial 3D growth mode**

**→ Goes polycrystalline in minutes**



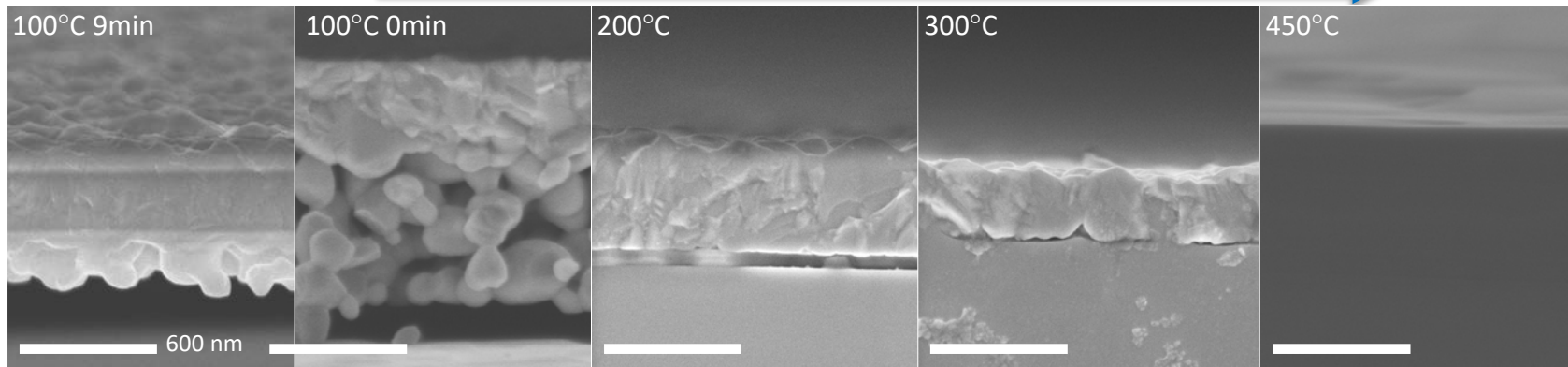


# GaAs on Salt: Growth Temperature – Ramped

GaAs deposited on 30 nm thin NaCl layers at  $T_{\text{initial}} \rightarrow 580^{\circ}\text{C}$

- $T_{\text{initial}} = 100^{\circ}\text{C} \rightarrow$  Porous interface + NaCl
- $T_{\text{initial}} = 200^{\circ}\text{C} \rightarrow$  Dense interface + NaCl
- $T_{\text{initial}} \geq 450^{\circ}\text{C} \rightarrow$  Homoepitaxy + No NaCl

Increasing initial deposition temperature 

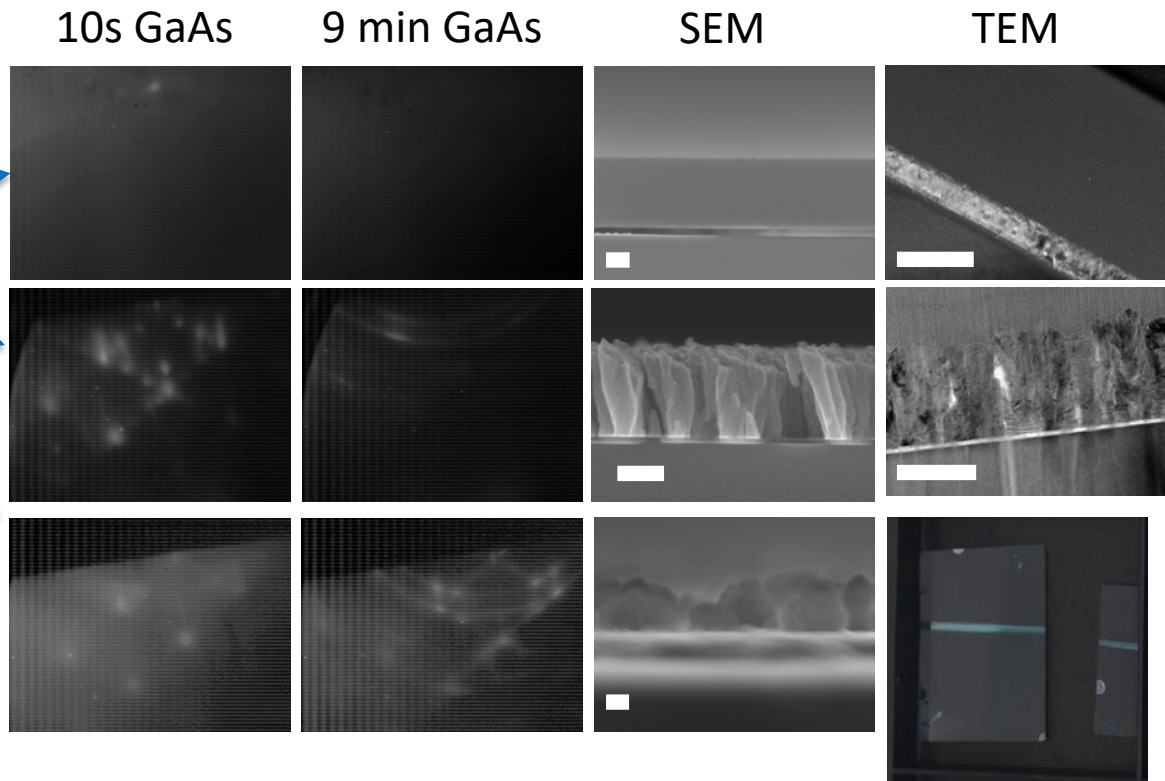


# GaAs on Salt: Growth Temperature – Constant

**Lower temperatures to ensure NaCl remains**

- 100°C=amorphous
- 250°C=columnar
- 300°C=crystallites

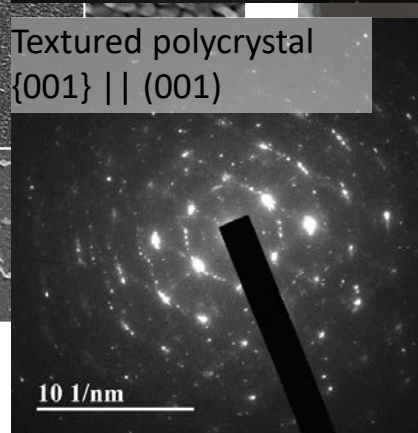
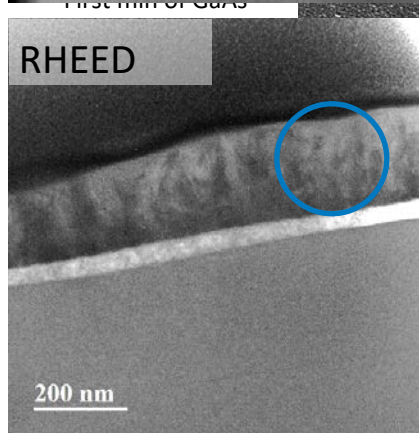
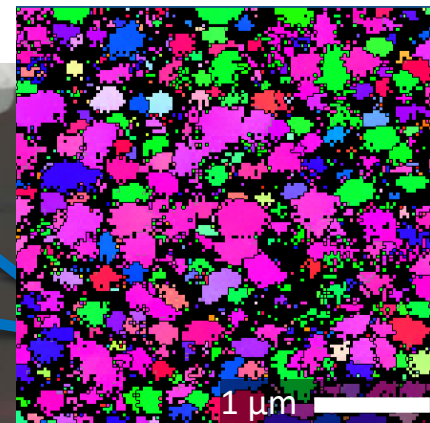
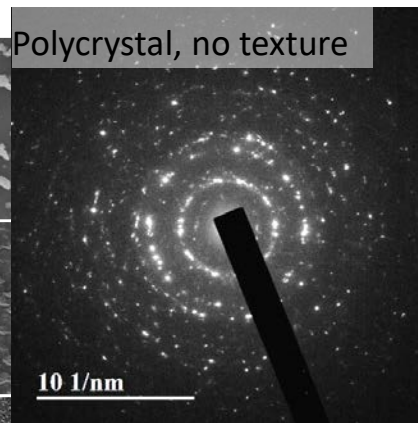
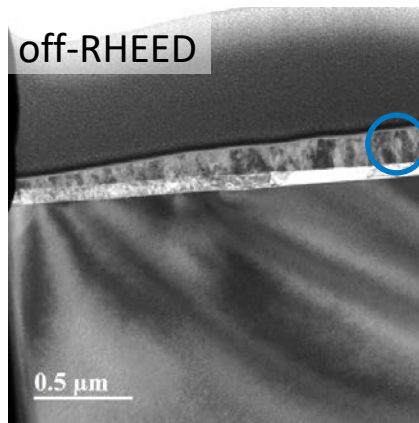
**But the RHEED seems to be doing something to the sample**



# Effects of the RHEED Beam

## TEM and EBSD

- **RHEED exposure**  
= textured and larger grains
- **15kV RHEED moved around**  
during initial growth stages
- **Away from RHEED** – islands  
on smooth NaCl
- **90s pre-GaAs** – rough (not  
NaCl) underlayer, wavy islands
- **1<sup>st</sup> min GaAs** – 25nm features,  
no islands at all
- **2<sup>nd</sup> min GaAs** – wavy islands  
with featured surface



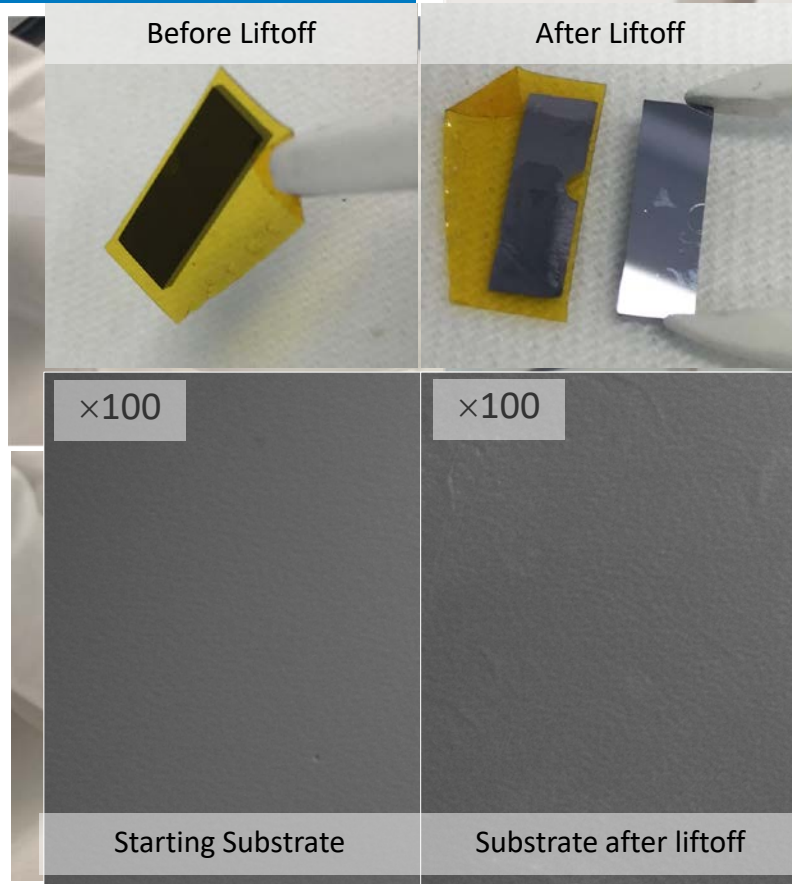
# Liftoff of Overlayer in Water

**Liftoff occurs quickly in water**

- Delaminates and curls without backing
- Kapton tape keeps overlayer from breaking/curling
- Can even be dry-peeled

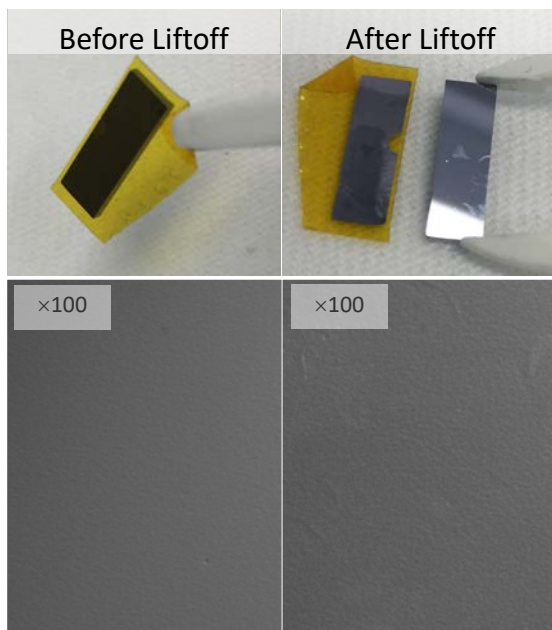
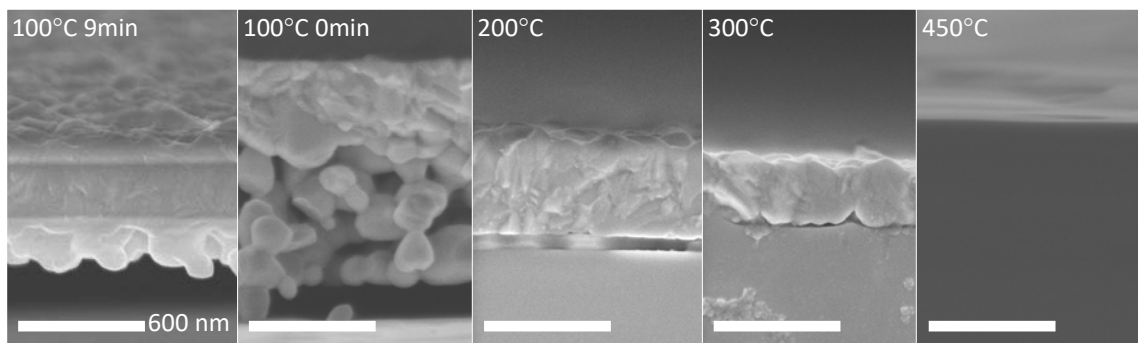
**Comparable surface post-liftoff**

- Regrowth should be possible



# Conclusion

- Epitaxial NaCl thin films deposited on GaAs
- Highly temperature dependent GaAs overlayer crystallinity/morphology
- RHEED greatly affects initial growth of overlayer
- NaCl layer dissolves quickly in water facilitating liftoff





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David Young

# Thank You

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